

## References

1. Nam-Trung Nguyen, and Steven T. (1969) *Fundamentals and Applications of Microfluidics: Commercial Aspect*. Artech House Publishers
2. NIHERST, (2005). Make Way For Microfluidics,  
<http://www.niherst.gov.tt/scipop/scibits/microfluidics.htm>
3. MIFLUS, (2003) Microfluidics terminology,  
[http://butler.cc.tut.fi/~kuncova/MIFLUS/microfluidics\\_termtree.php](http://butler.cc.tut.fi/~kuncova/MIFLUS/microfluidics_termtree.php)
4. Marc J Madou Fundamentals of Microfabrication . The Science of Miniaturization 2<sup>nd</sup> Edition. C.R.C Press
5. Nam-Trung Nguyen, and Steven T. (1969) *Fundamentals and Applications of Microfluidics: What is Microfluidics*
6. FreePatentsOnline, (2004). Fluid level sensor having capacitive sensor,  
<http://freepatentsonline.com/5182545.html>
7. ANSYS, (2006) Microsystem Analysis Example Application,  
<http://www.ansys.com/industries/mems/mems-application-channel.asp>
8. Barry M. Lunt, (2004), *Electronic Physical Design*, Prentice Hall, pp 55, 63, 64, 70, 74, 76, 94, 99, 100, 177, 238, 273
9. Sunny TH Goh, Khoo Keng Hor, *Marketing \*Wise Approach To Strategic Marketing in Asia* (2003), Prentice Hall.
10. Monckza, Trent, Handfield, *Purchasing and Supply Chain Management* 2<sup>nd</sup> Edition
11. S. Poorna Chandra, B. Sasikala, *Electron Devices*, pp.3.17
12. Micheal Shur (1995), *Introduction to Electronic Devices*, pp 12
13. Keith Brindley (2005), *Starting Electronics Construction*, pp 38, 40, 41, 39
14. Charles A. Harper (2002), *electronic Assembly Fabrication*, pp 306
15. Neil Storey (2006), *electronics A Systems Approach*, pp 185, 201
16. Subash Mahajan, K.S. Sree Harsha (1999), *Principle of Growth and Processing of Semiconductors*, pp 448-480

17. Jan G. Korvink, Andreas Greiner (2002), Semiconductor for Micro and Nano Technology, pp 29, 33, 36
18. Q.-Y. Tong, U. Gosele (1999), Semiconductor Wafer Bonding Science and Technology pp. 103-138
19. Kwok K. Ng (1995), Complete Guide to Semiconductor Devices, pp 121-142
20. M.S.Tyagi (1991), Introduction to Semiconductor Materials and Devices, pp 590, 592
21. E. Ajith Amersekera, Farid N. Najm (1997), Failure Mechanisms in Semiconductor Devices pp 309
22. R. Qiao and N. R. Aluru Beckman, A Compact Model for Flowrate and Pressure Computation in Micro-fluidic Devices, Institute for Advanced Science and Technology University of Illinois at Urbana-Champaign 405 N Mathews Avenue, Urbana, IL 61801
23. T D James, G Parish, K JWinchester and C A Musca, A crystallographic alignment method in silicon for deep, long Microchannel fabrication, Microelectronics Research Group, School of Electrical, Electronic and Computer Engineering, The University of Western Australia, Perth, Australia
24. B T Yang<sup>1,2</sup>, M Bonis<sup>2</sup>, H Tao<sup>1</sup>, C Prella<sup>2</sup> and F Lamarque<sup>2</sup>, A magnetostrictive mini actuator for long-stroke positioning with nanometer resolution, Northwestern Polytechnical University, Xi'an 710072, People's Republic of China, <sup>2</sup> Universit'e de Technologie de Compi'egne, Compi'egne 60203, France
25. Mark A Eddings and Bruce K Gale, A PDMS-based gas permeation pump for on-chip fluid handling in microfluidic devices, Department of Bioengineering, University of Utah, Salt Lake City, UT 84112, USA Department of Mechanical Engineering, University of Utah, Salt Lake City, UT 84112, USA
26. Mats J'onsson and Ulf Lindberg, A planar polymer microfluidic electrocapture device for bead immobilization, Solid State Electronics Department, The Angstrom Laboratory, Uppsala University, PO Box 534, SE-751 21 Uppsala, Sweden
27. Dong Yan and Amit Lal, Silicon-on-insulator cantilevers as charge collectors for radioisotope micropower sources: design, fabrication and characterization, 406 Phillips Hall, School of Electrical and Computer Engineering, Cornell University, Ithaca, NY 14853, USA

28. Changju Wu, Zhonghe Jin, Huilian Ma, Shoufeng Lin and Yuelin Wang, Sacrificial layer etching process in joint channels, Department of Information and Electronic Engineering, Zhejiang University, Hangzhou 310027, People's Republic of China
29. Seung Mo Kim, Woo Il Lee and Kahp Y Suh, Evolution of transient meniscus in a wettable microchannel for Newtonian fluid, School of Mechanical and Aerospace Engineering, Seoul National University, Seoul 151-742, Korea
30. Biao Li, Thomas Schwarz and Andre Sharon, Implementation of microfluidic devices at a transparency, Fraunhofer USA Center for Manufacturing Innovation, Brookline, MA 02446, USA.
31. Yu-Jen Pan and Ruey-Jen Yang, A glass microfluidic chip adhesive bonding method at room temperature, Department of Engineering Science, National Cheng Kung University, Tainan, 701, Taiwan.
32. Brian J Adzima and Sachin S Velankar, Pressure drops for droplet flows in microfluidic channels, Department of Chemical Engineering, University of Pittsburgh, Pittsburgh, PA 15261, USA